

New concepts for yield improvements and selective repair of cantilever pins for Flash and DRAM probe cards



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Outline

- Short Company Profile
- Introduction in Cantilever Assembly
 - General Process Flow & Specs
 - Improvements during 10 years manufacturing of cantilever bonder
- Temperature Control
- Selective Cantilever Repair/Rework
- Wire Soldering
- Summary/Outlook

Company Profile

- 1995 Founded in Berlin, Germany as spin-off from Fraunhofer-IZM
- 1997 1st Manufacturing facility: PacTech GmbH, Nauen, Germany
- 2001 2nd Manufacturing facility: PacTech USA Inc., CA, USA
- 2005 Equipment Field Service & Support Center, Thailand
- 2008 3rd Manufacturing facility: PacTech Asia Sdn. Bhd., Malaysia
- 2013 > 115 patents granted
- 2014 Demo Center Opening: Hsinchu, Taiwan
- 2015 Demo Center Opening: Shanghai, China
- 2015 100% owned by NAGASE & Co. Ltd.
- 2018 > 1,300 Production Machines shipped
 - ~ 420 employees



Company Profile



Certified ISO 9001, IATF 16949, ISO 14001, ISO 50001

Cantilever Assembly

Cantilever Bonding/Assembly



Cantilever Singulation (Laser Cutting)

Cantilever Inspection

Cantilever Sorting (into waffle packs) if needed

Substrate Solder Bumping

Cantilever / Substrate Alignment

Cantilever Laser Bonding

Cantilever inspection (optional)

Cantilever Assembly Line

Cantilever Sorter

Solder Jetting: SB²-Jet

Cantilever Bonder: Laplace-Can



Features

- ✓ Input: MEMS substrates
- Inspection of cantilever
- Laser cutting
- Placement of singulated cantilever in waffle packs

Features

- ✓ Solder Jetting on substrate
- Solder Balls sizes: 30 μm – 760 μm
- Solder alloys capability: PbSn, SnAgCu, AuSn



Features

- Cantilever supplied in waffle packs
- Cantilever pick & rotation in vertical position
- ✓ Substrate height measurement
- Dual camera for x, y alignment of cantilever to the substrate
- Probe tip z alignment
- Laser bonding of cantilever
- Post inspection (optional)
- Cantilever rework capability

Cantilever Bonder Specifications

- Linear axis or gantry system
- Probe card sizes up to 14 inch
- Alignment by precision optical system
- Tip correction (bend)
- IR laser for solder reflow
- Placement Accuracy: +/- 3.5µm
- Z height control: +/- 4.0µm
- ➤ Hump tilt: +/- 3.0µm
- Cantilever thickness: min 20µm
- Pitch: min 50µm
- Process suitable for complete card assembly and selective rework
 Post Bond inspection (optional)
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Cantilever Assembly (80µm pitch)



Improvements

Cycle Time Roadmap

2009 process development first machine <30 sec 2014 Mass production <15 sec

2018 Mass production <9 sec

2012 Mass production <20 sec 2016 Mass production <12 sec 2019 Mass production < 8 sec

One cycle: Cantilever pick-up, Alignment, Bonding

Improvements

Machine Performance Data

MTTF:	250 hrs for process (pin transfer alignment failure)					
MTTF:	400 hrs for machine					
MTTA:	Alignment failure < 2h					
MTTR:	< 4h					
Uptime:	95%					
Cycle time:	8 sec for 1pin					
Yield:	>98% @+/-4um					
22hr working condition; > 6,000pin bonded						



Cantilever Assembly 360°

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Video Cantilever Assembly



Temperature Control

Temperature Control Overview

- Temperature is detected by a pyrometer
- Temperature is controlled by a PID software controller
- Temperature values can be set for each single bond profile step, as well as the controller parameters (Kp, Ki, Kd)
- Choice in between temperature control and simple laser value (current version) for each single bond profile step
- First successful tests have been finished (± 2µm accuracy)



Bond Tool & Temperature Control Unit

Temperature Control Bond Parameter

- Examples of Temperature settings
- if the temperature value is zero, the laser parameter is used for this single step
- Setting of controller parameters (Kp, Ki, Kd) for each single step

nd Parameter			23	Bond Para	meter
Parameter Sets Bond parameter set: Description:	0000 Set no. 0000	•	New Delete Clone	Param Bond Desc	eter Sets parameter s ription:
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Offset to Substrate: Profile Time (0 = Profile disabled): Laser current : Temperature : Maximum force: Mount :	300 300 3800 300 120 50	[μm] [ms] [0 - 1 [mA] [0 - 1 [°C] [0 = α [g] [10 - [μm] [100	0000) 0000) disabled] 2000] 0. 1000]	Offse Profile 2 Time Laser Temp Maxim	t to Substrat
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Description:	Set no.	0000		Delete	
				Clone	
Substrate height :		19.648	[mm]	[-15 - 100] Set	
Start level (above substr	at height) :	95	[μm]	[0 - 5000]	
Safe level (up after bond):	17.405	[mm]	[0 · 20]	
Pre Bond Y Offset:		0	 [μm]	[·1000 · 1000]	
Height measurement with	n	C Height Sensor • Force Sensor			
Maximum Force:		40	_ [9]	[10 - 100]	
Offset to Substrate:		300	 [μm]		
Time (0 = Profile disabled): Laser current : Temperature : Maximum force: Move :		200 4000 350 120 -55	[ms] [mA] [°C] [g] [μm]	[0 - 10000] [0 - 10000] [0 = disabled] [10 - 2000] [-1000 - 1000]	
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Controller Pa Kp Ki: Kd	rameters— : :	2 0.08 20	-		
-		0.075	- (mm)/	[9]	

√ Laplace-Can Temperature Control

- Used temperature control (Original: Laser current control)







- ✓ Compare with Laser current control, the temp control show 0.8 sec less cycle time.
- ✓ New type bonder: EQ859

Expectation to reduce the bonding cycle time down to 6.8 sec in max case.

√ Temperature Control

	Profile	Temperature (°C)	Diagram
	1	0 (=disabled)	
Laser current control	2	0 (=disabled)	
	3	0 (=disabled)	
	4	0 (=disabled)	41 40 46 (0) 41 (0) 42 (0) 42 (0) 42 (2)
	1	230	
T error control 4	2	230	
Temp control 1	3	230	
	4	0	0 34/01 38/70 29/10 38/10 38/10 38/10
	1	230	
	2	230	
Temp control 2	3	230	
	4	0	6 301-255 302-255 302-255 302-255 302-255
Temp control 3	1	200	
	2	200	
	3	200	
	4	0	near and a line with a line with a line with a set
	1	190	
Temp control 4	2	190	
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	4	0	Publication 1 <th1< th=""> 1 <th1< th=""> 1 <th1< th=""> <th1< <="" td=""></th1<></th1<></th1<></th1<>

√ Solder melting

	Temp control 1	Temp control 2	Temp control 3	Temp control 4
Solder melting Image	No image			
Condition	Good	Good	Good	Not bad

√ Bonding Test (Align)

- bond parameter tuning for stabilization still ongoing



- \checkmark Shear force test
 - All cantilever off
 - Shear force : 45~60g
 - Good status

Temp 220°

Test Detail Туре Grade Description Test Force 5 Cantilever off 54.52 g Pass Cantilever off 49.96 g Pass 5 .> 49.65 g Pass 5 Cantilever off 46.61 g Pass 5 Cantilever off 43.07 g Pass 5 Cantilever off 45.23 g Pass 5 Cantilever off 43.37 g Pass 5 Cantilever off 41.96 g Pass 5 Cantilever off 51.48g Pass 5 Cantilever off 44.71 g Pass 5 Cantilever off 10 46.02g Pass 5 Cantilever off 11 12 45.25 g Pass 5 Cantilever off Cantilever off Pass 5 13 57.04 g Cantilever off 57.60 g Pass 14 Cantilever off 15 38.06 g Pass 16 49.23 g Pass Cantilever off

Temp 230°

Test Detail

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Test

3

4

Temp 230°

brce 1.57 g 4.75 g 4.09 g 9.24 g 5.89 g 7.97 g 9.41 g 9.07 g	Type Pass Pass Pass Pass Pass Pass Pass Pas	Grade 5 5 5 5 5 5 5 5 5 5 5 5	Description Cantilever off Cantilever off Cantilever off Cantilever off Cantilever off Cantilever off Cantilever off	Test	Detail Test 1 2 3 4 5 6 7 8	Force 56.15 g 55.01 g 51.41 g 56.78 g 52.66 g 46.64 g 37.39 g 48.69 g	Type Pass Pass Pass Pass Pass Pass Pass Pas	Grade 5 5 5 5 5 5 5 5 5	Description Cantilever off Cantilever off Cantilever off Cantilever off Cantilever off Cantilever off Cantilever off Cantilever off	
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Selective Cantilever Repair/Rework

Major functions and rework possibilities

Following single functions are implemented and tested successfully:

- X-,Y- and Z-shifting and angle correction
- Detaching & gripper cleaning
- Spring correction
- Pre-bond tip inspection
- Bonding

The automatic process is under development and testing. Currently planned is the implementation of a selection of following automatic process functions:

- Pin shifting and angle correction of good but misaligned pins
- Detaching of bad pins
- Automatic repair including detaching and re-bonding

Failure mode: Bended Pin/Cantilever

- If the pin is bent at front side (tip) there's most likely not enough space for the gripper tool to move between other pins (pitch).
- The gripper tool length is designed to match to the hump length and is always aligned parallel to that one for gripping purpose.

Contact point position correction



The base for the gripper development was the latest standard Laplace-Can machine used for Cantilever bonding

The Laplace-Can machine platform is used to have the capability of loading a fully assembled wafer probe card and to guarantee the same axis performance and accuracy



Main components of the existing machine like camera alignment terminal, vacuum cleaning station and spring correction position can still be used.

The picture shows the gripper at the tip inspection position. The orientation of the tip is always to front side of the machine
 Necessary angle correction moves are performed by rotating the bonding table



This picture shows the changed main components located at the Gantry Z-axis.

Gripper axis system with integrated force sensors

Gripper tools



Direct drive motor with backlash free gear drive

Already existing force measurement (Z-direction)

Laser beam supply with prepared IR temperature measurement

Video Cantilever Rework



Wire Soldering

SB²-WB for probe card wire soldering

SB²-WB* is a combination of PacTech's SB²-Jet (solder ball jetting) process and a wire feeding mechanism

Principle process flow

- 1. Positioning of bond tool with respect to a solderable target position
- 2. Wire is pushed onto the target while parallel a solder ball is loaded into the jetting capillary
- 3. Liquid solder droplet is applied by laser and N_2 -pressure onto the wire located on the pad
- 4. Solder solidifies and generates a uniform interconnection between wire, solder and pad
- 5. System moves to a subsequent bond location while wire unwinds (loop-forming)
- 6. Previous process steps are repeated and the wire is cut



Fig.1: SB²-WB process principle

SB²-WB for probe card wire soldering

Advantages

- > Neither pressure, vibration nor high temperatures required
- > No transformation of wire diameter or change of bulk properties
- No loop option
- Flexible bond tool configuration in a hemispherical workspace
- Bonding of thick and fine wires, even with insulation coating
- Wide range of wire materials: Au, Ag, Cu, Pd, Pt etc.
- Conventional loop forming or no loop options



- Full automatic process solution for soldering of wires in the peripheric area of probe cards
- Automated contact of pin to board via wire



SB²-WB wire-bonds



SB²-WB loop formation

Video Wire Soldering



Summary

The following was shown:

- Improvements on Cycle Time and Machine Performance for an established Cantilever Assembly Process
- Implementation of Temperature Control as important feature for laser bonding stability
- Introduction of a new process as a possibility for for selective Cantilever rework either inline or as stand-alone equipment
- Introduction of Laser Wire Soldering for the electrical connection of passive components, connectors and other components

Thank You!



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